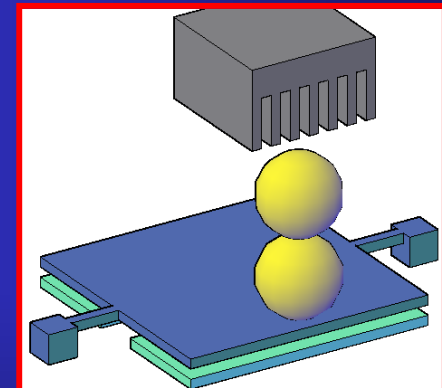
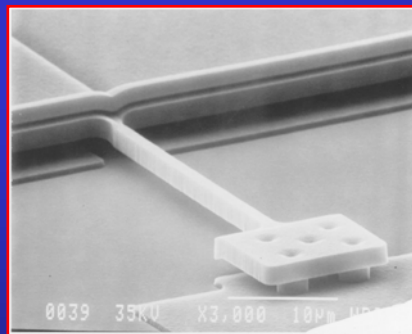
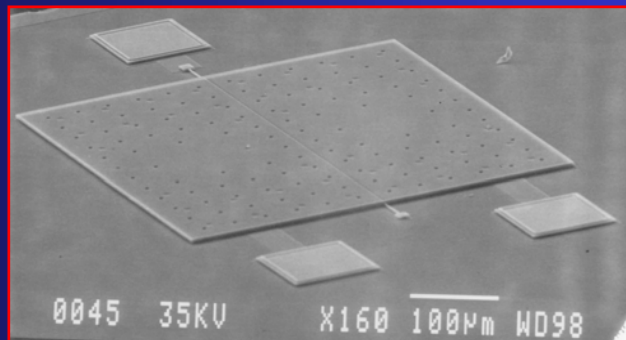
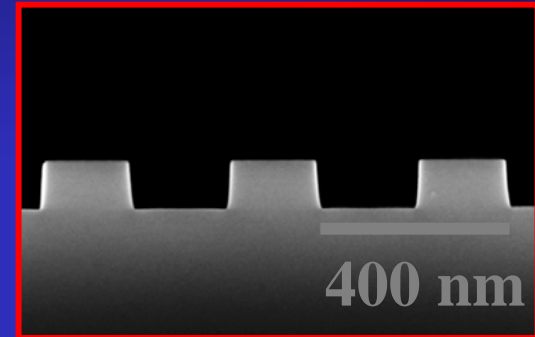
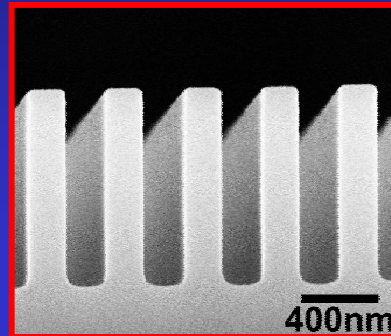


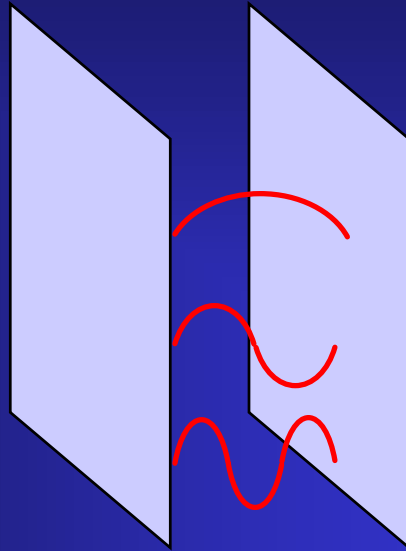
Measuring the Geometry Dependence of the Casimir force on Nanostructured Silicon Surfaces

Ho Bun Chan

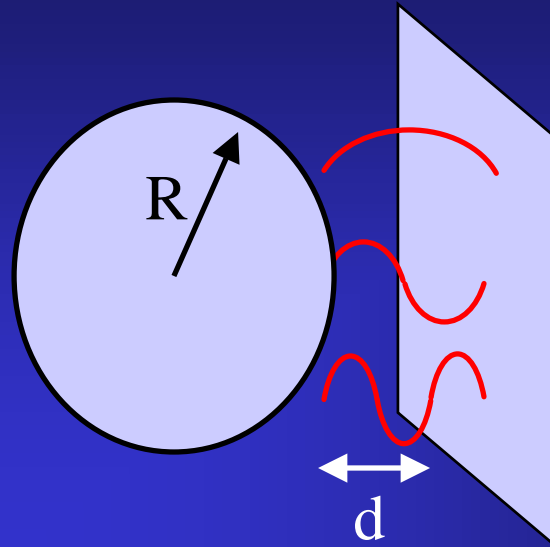


September 29th, 2009. Casimir force control, Santa Fe, NM.

Reducing the effective area of interaction

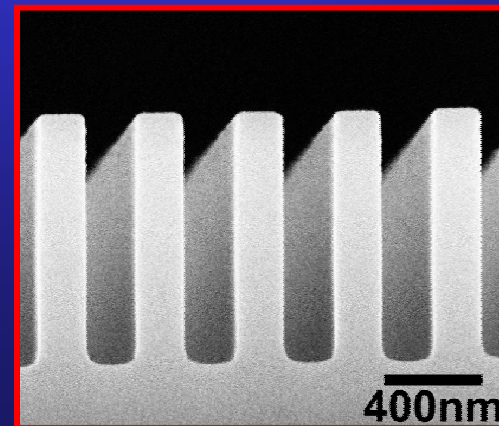
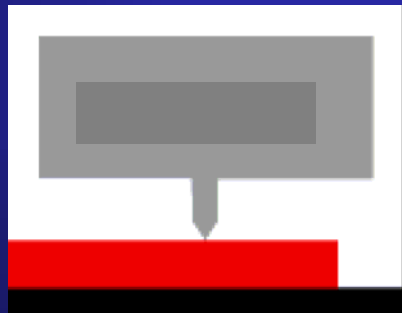


$$F_{Casimir} = -\frac{\pi^2 \hbar c A}{240 d^4}$$



$$F_{Casimir} = -\frac{\pi^3 R \hbar c}{360 d^3}$$

Dimples to minimize stiction



$$F_{casimir} = \frac{1}{2} F_{flat} ?$$

$$F_{casimir} > \frac{1}{2} F_{flat} ?$$

$$F_{casimir} < \frac{1}{2} F_{flat} ?$$

Outline

- Non-trivial dependence of the Casimir force on geometry:

Proximity Force Approximation (PFA)

Pairwise Additive Approximation (PAA)

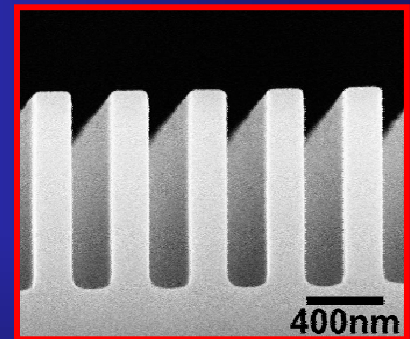
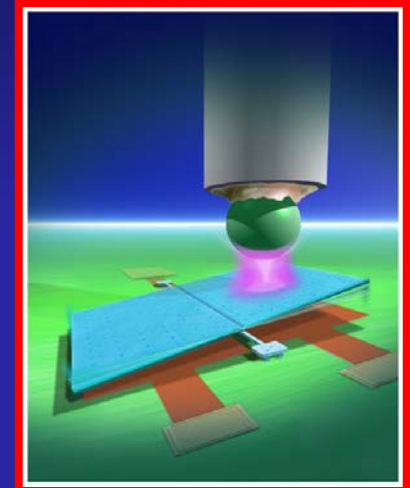
- Experiment on strongly deformed surface:

Measure Casimir force on an array of nanoscale trenches with a micromechanical torsional oscillator.

Up to 30% deviation from PFA and PAA.

Evidence of non-trivial boundary dependence of the Casimir force.

~ 30% smaller than theory on perfect metals.



Collaborators

University of Florida

Yiliang Bao

Jie Zou

University Paris-Sud

Thorsten Emig

UT Brownsville

Andreas Hanke

MIT

Steven Johnson

Bell Labs

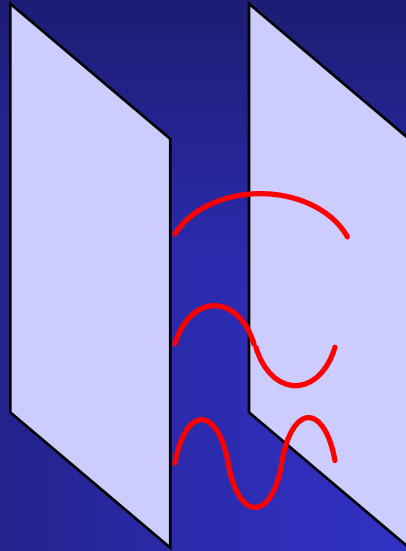
Ray Cirelli

Fred Klemens

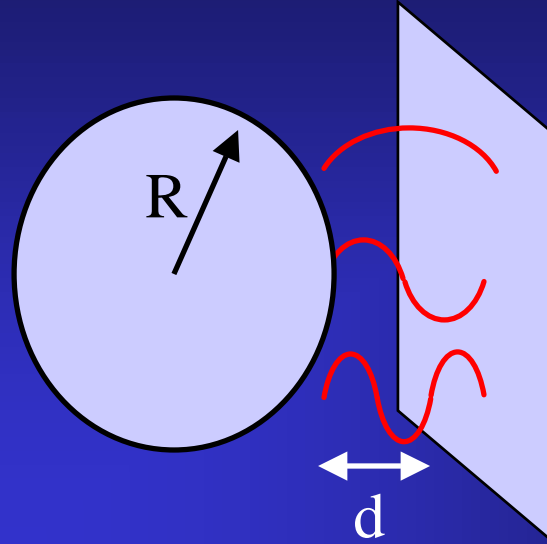
Bill Mansfield

C.S. Pai

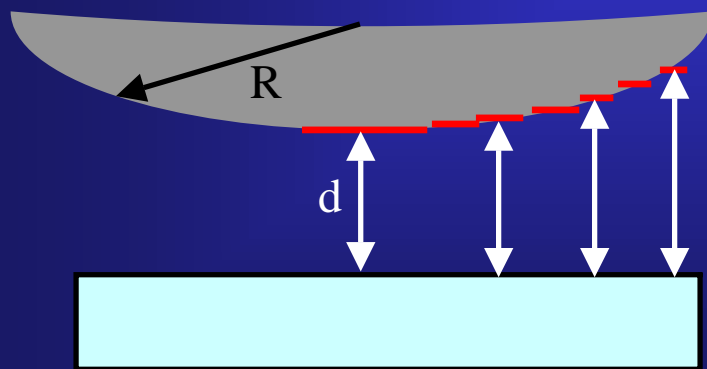
Geometry dependence of the Casimir force



$$F_{Casimir} = -\frac{\pi^2 \hbar c A}{240 d^4}$$



$$F_{Casimir} = -\frac{\pi^3 R \hbar c}{360 d^3}$$

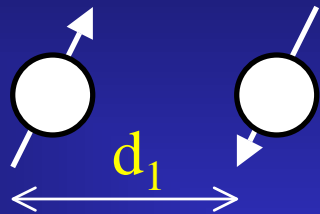


Two common ways to obtain the Casimir force for non-planar objects:

PFA: Proximity force Approximation (Derjaguin approx)

PAA: Pairwise Additive Approximation

Quantum fluctuations: Casimir force vs van der Waals' force



$$d_1 < c \tau$$

$$V_{vdw} = -\frac{B}{r^6}$$



$$d_2$$

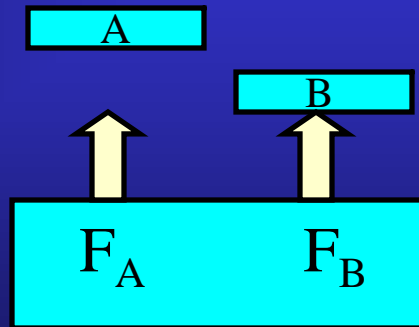


$$d_2 > c \tau$$

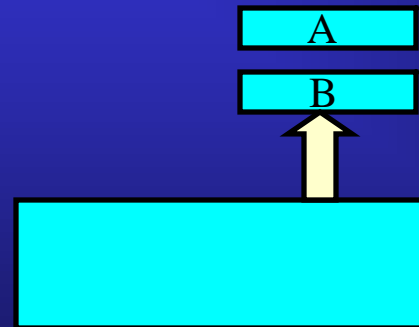
$$V_{retarded\ vdw} = -\frac{B'}{r^7}$$

retardation effects: finite propagation speed of light

Non-pairwise additivity



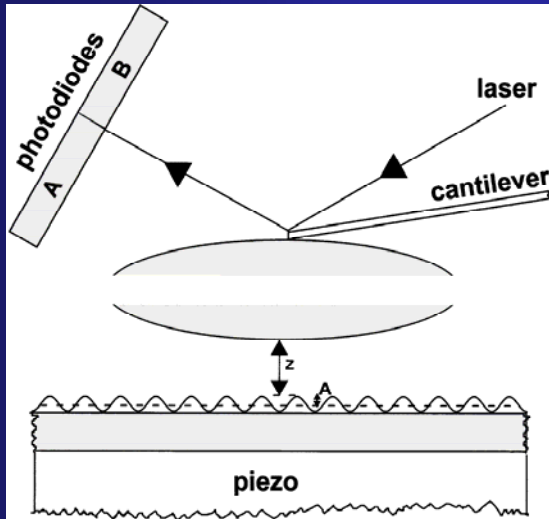
$$F_{total} \sim F_A + F_B$$



$$F_{total} \neq F_A + F_B$$

Casimir force measurements on deformed surfaces

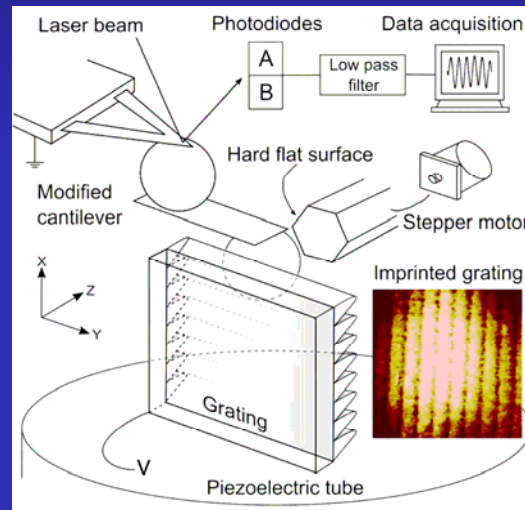
UC Riverside



Roy & Mohideen,
1999.

Normal force on sinusoidal
corrugations

UC Riverside

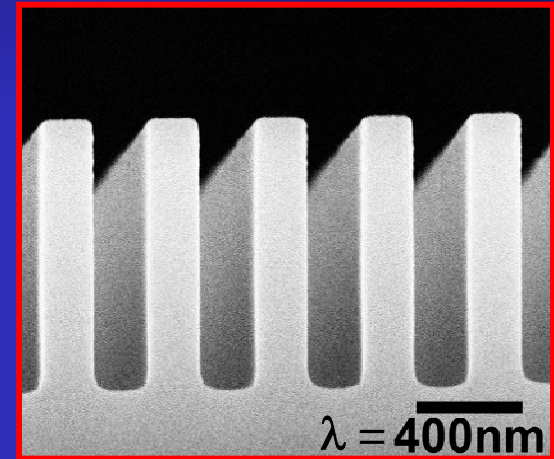


Chen et al., 2002.

Chiu et al., 2009.

Lateral force on sinusoidal
corrugations

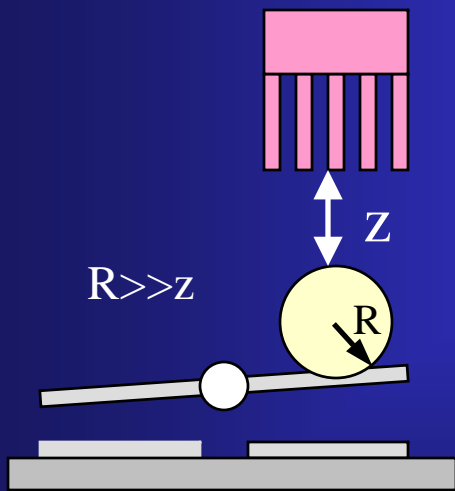
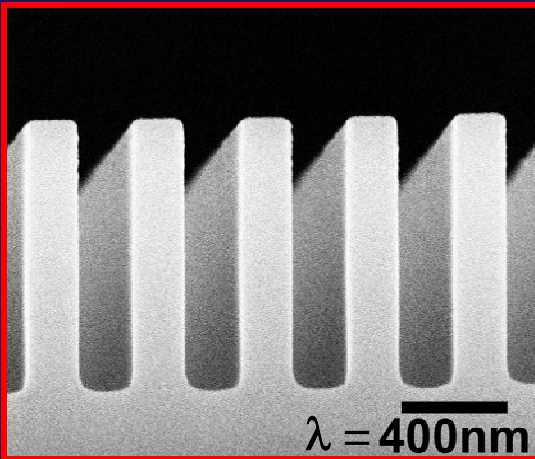
University of Florida



Chan et al., 2008.

Normal force on deep
rectangular corrugations

Non-trivial boundary dependence of the Casimir force

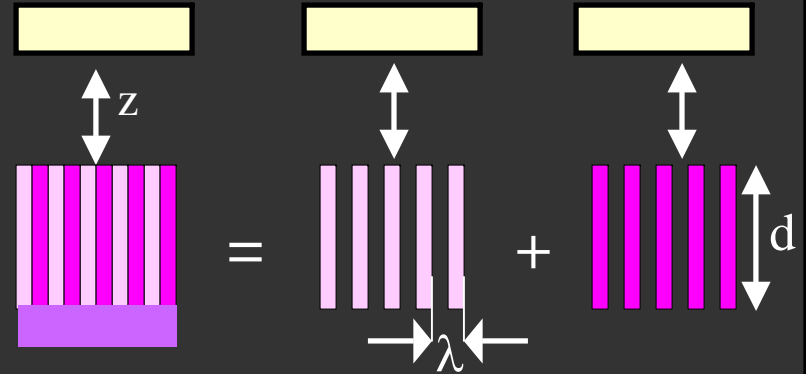


Chan et al., PRL 101, 030401 (2008).

Pairwise additive approximation (PAA)

If $d \gg z$, for all λ ,

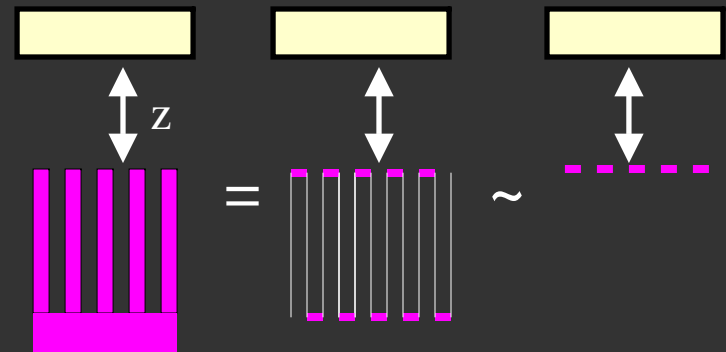
$$F_{\text{corrugated}}(z) = \frac{1}{2} F_{\text{flat}}(z)$$



Proximity force approximation (PFA)
(Derjaguin approx)

If $d \gg z$, for all λ ,

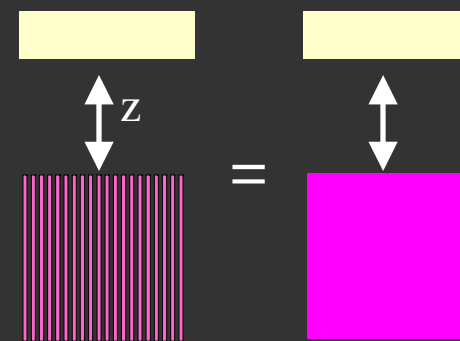
$$F_{\text{corrugated}}(z) = \frac{1}{2} F_{\text{flat}}(z)$$



Casimir force for perfect metal

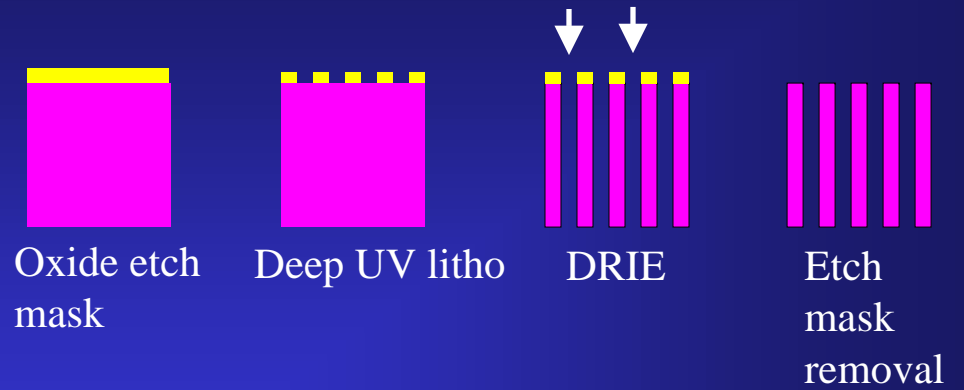
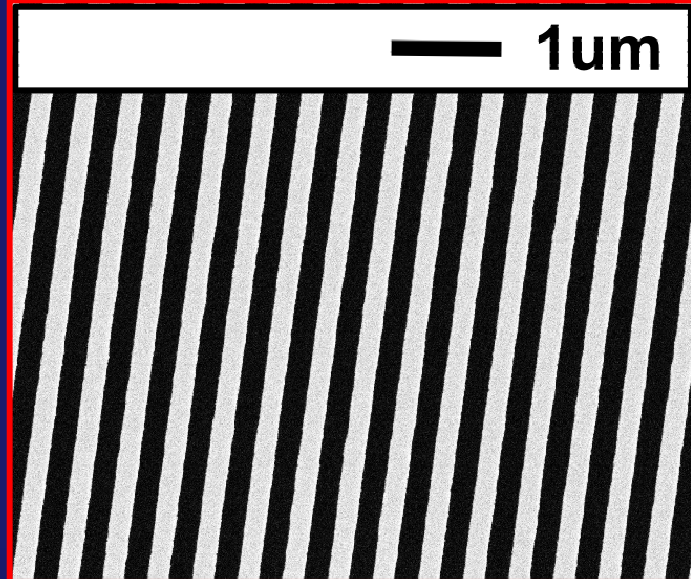
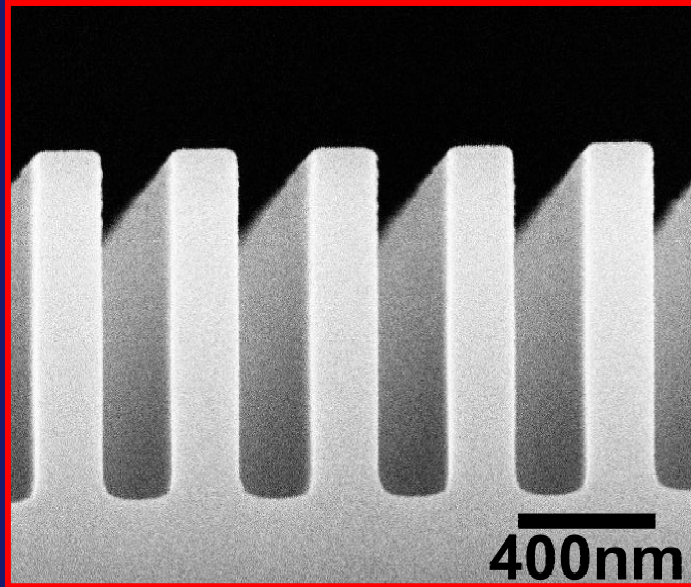
for $\lambda \ll z$,

$$F_{\text{corrugated}}(z) = F_{\text{flat}}(z)$$



Buscher & Emig, PRA 69, 062101 (2004).

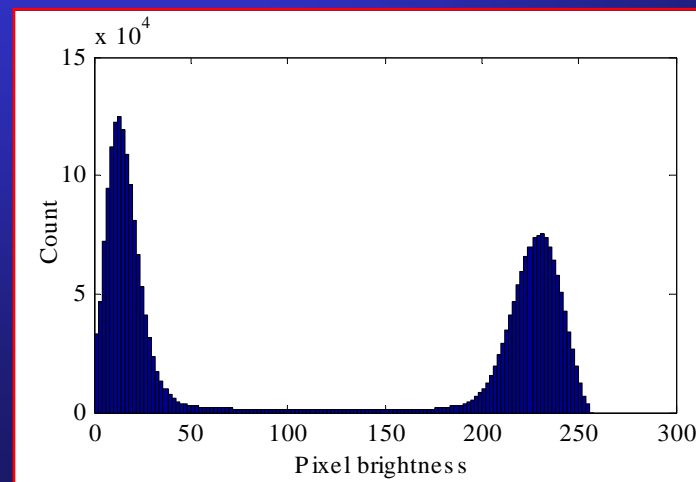
Sample fabrication and characterization



Solid fraction $p = 0.51 + 0.001$

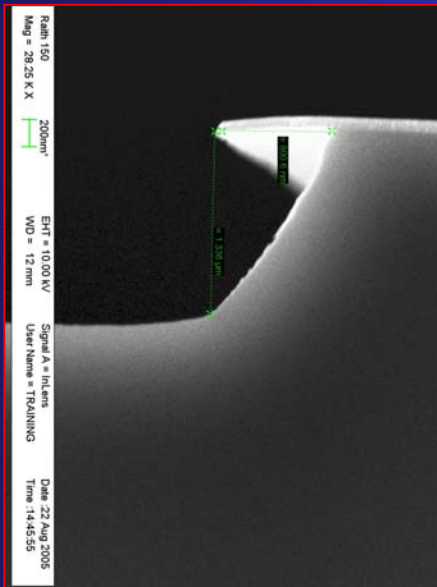
histogram of pixel brightness in top view
average from 10 pictures

Depth = 1.07 um

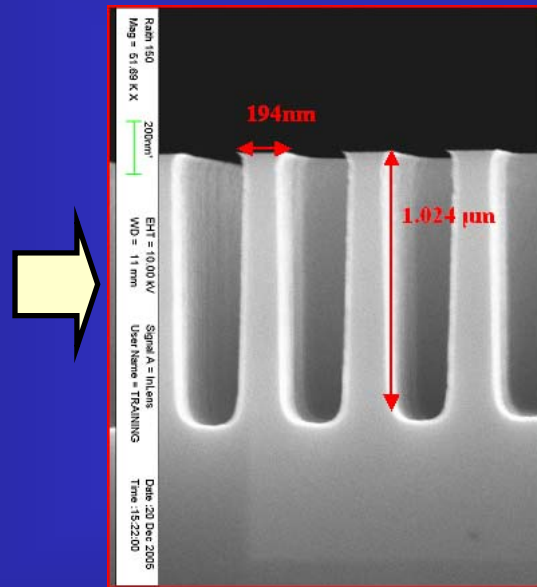


Developing etching recipe for vertical sidewalls

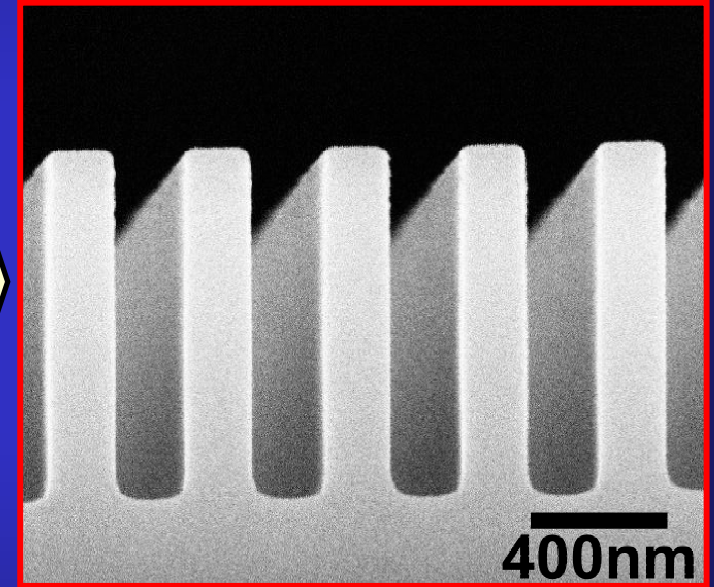
1st week



4 months

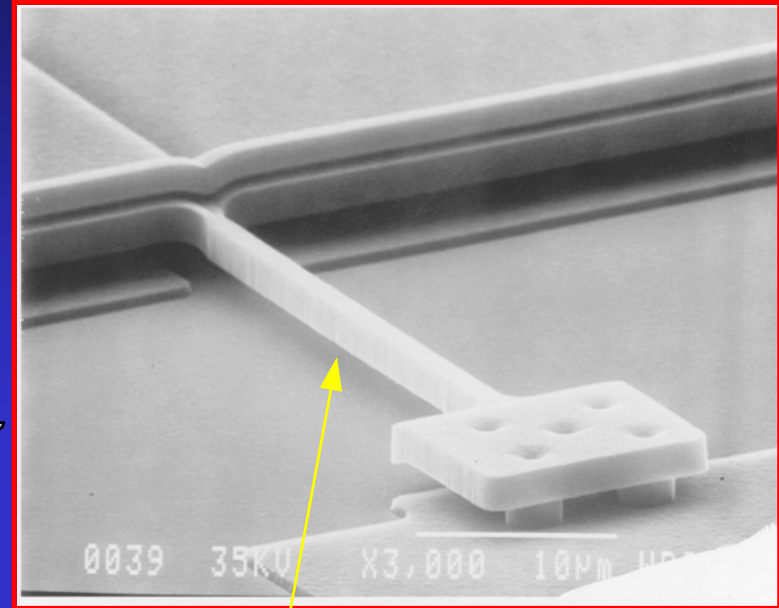
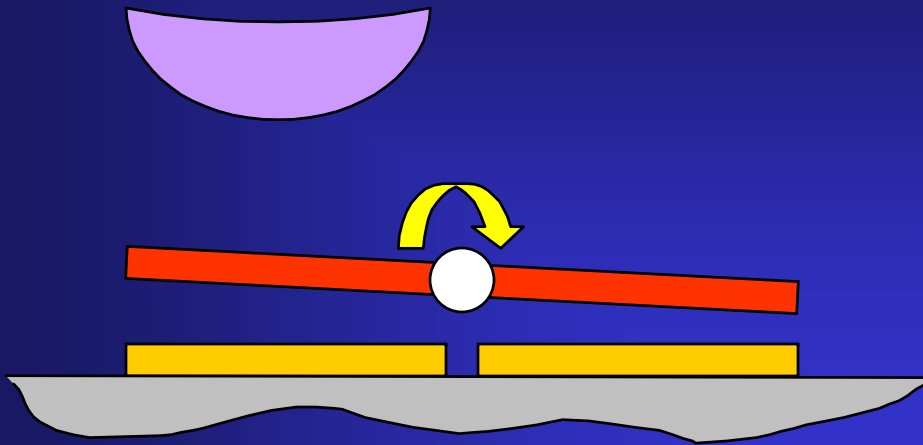


12 months

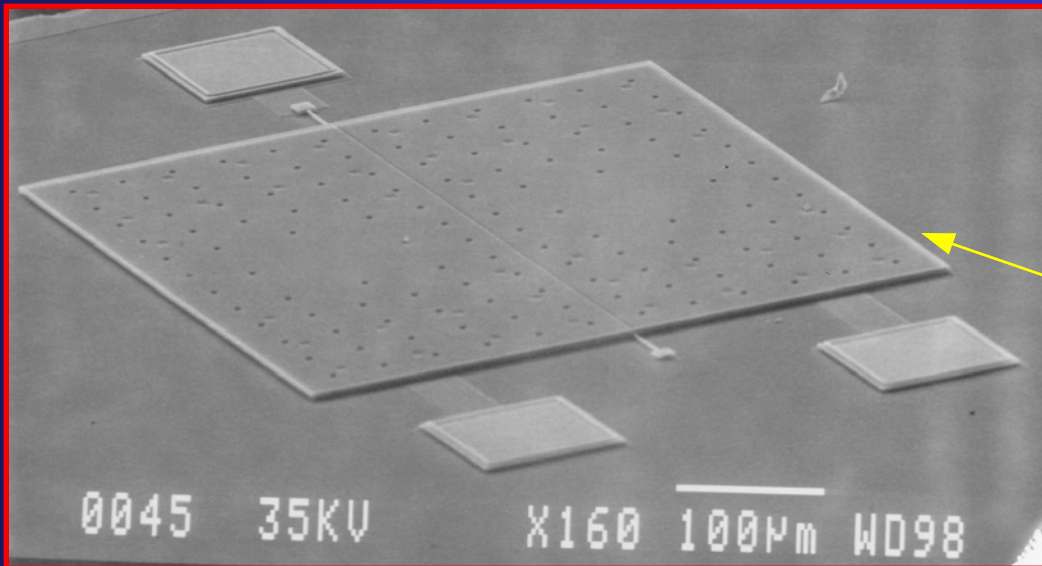


Etching performed by J. Zou and Y. Bao at University of Florida Nanofabrication Facility

Micromechanical torsional oscillator



Torsional rod
cross section: $1.5 \times 2 \mu\text{m}^2$

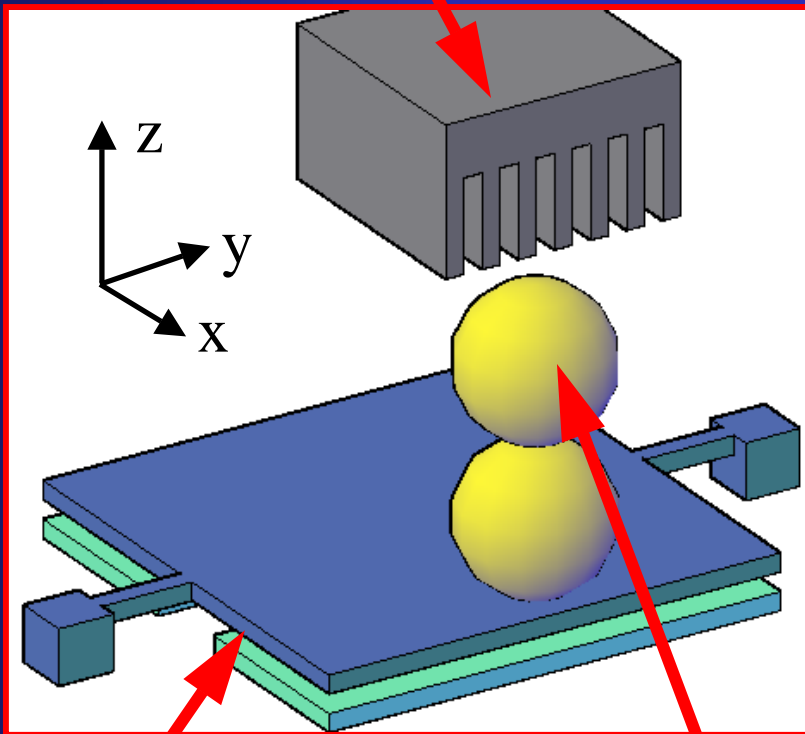


poly-Si plate:
 $500 \mu\text{m} \times 500 \mu\text{m} \times 3.5 \mu\text{m}$

Experiment setup

Sample orientation eliminate lateral motion.

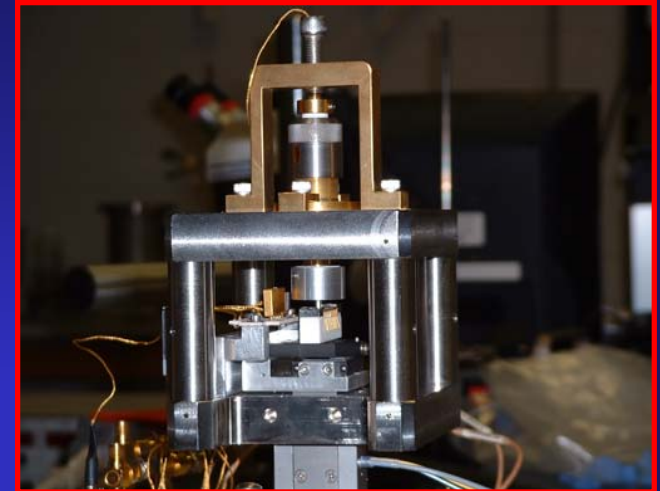
Immediately before pump down
HF remove native oxide layer, hydrogen
termination of the surface



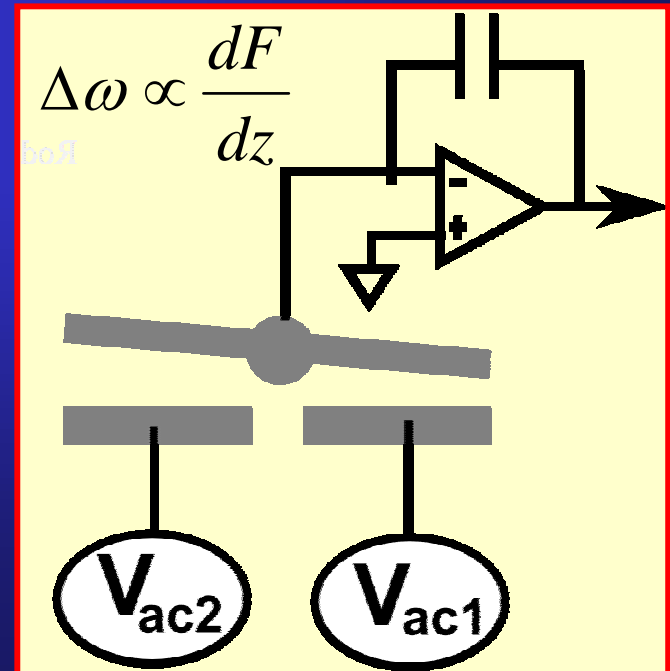
poly-Si plate:
500 μm x 500 μm x 3.5 μm

Glass sphere: $d \sim 100 \mu\text{m}$

Sputtering: 400nm gold



$\sim 1 \text{ nm/hour}$ drift in z



Calibration by electrostatic force

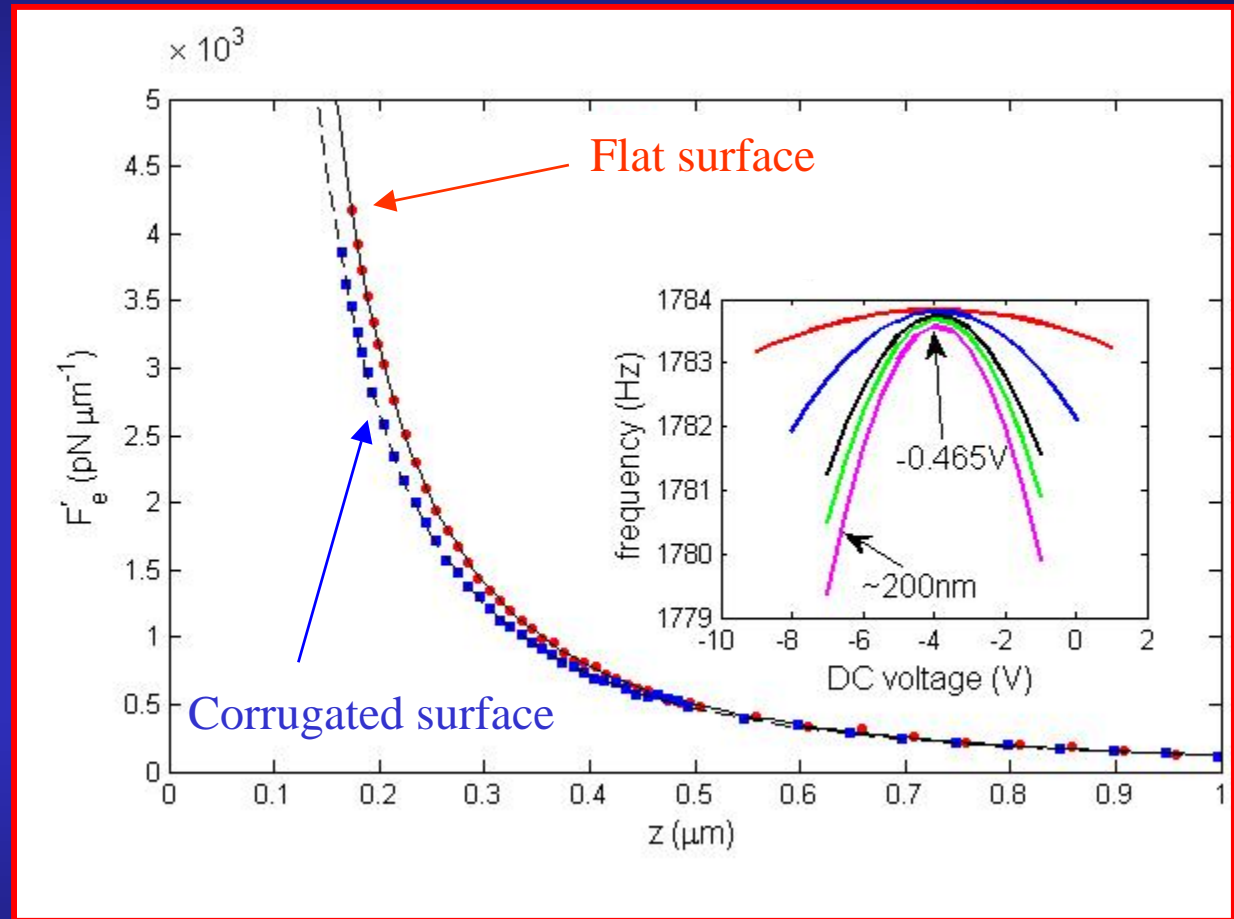
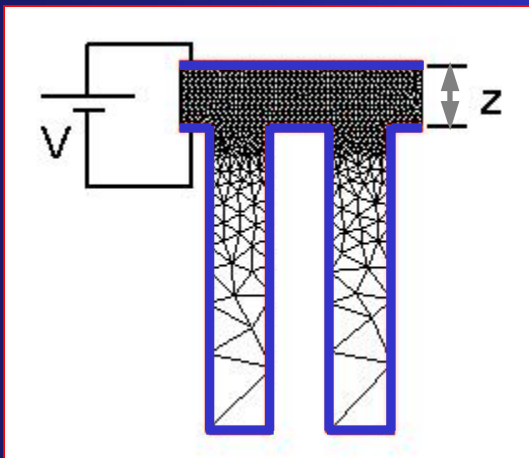
Flat surface

$$F'_e = \varepsilon_0 \pi R \frac{(V - V_0)^2}{(z + z_0)^2}$$

V_0 : residual voltage

z_0 : closest approach distance

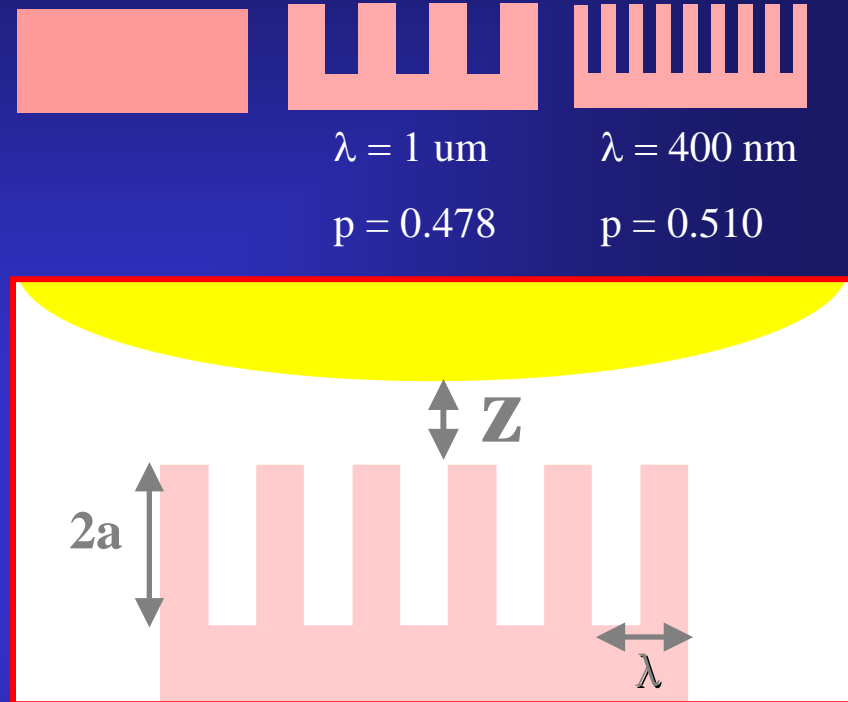
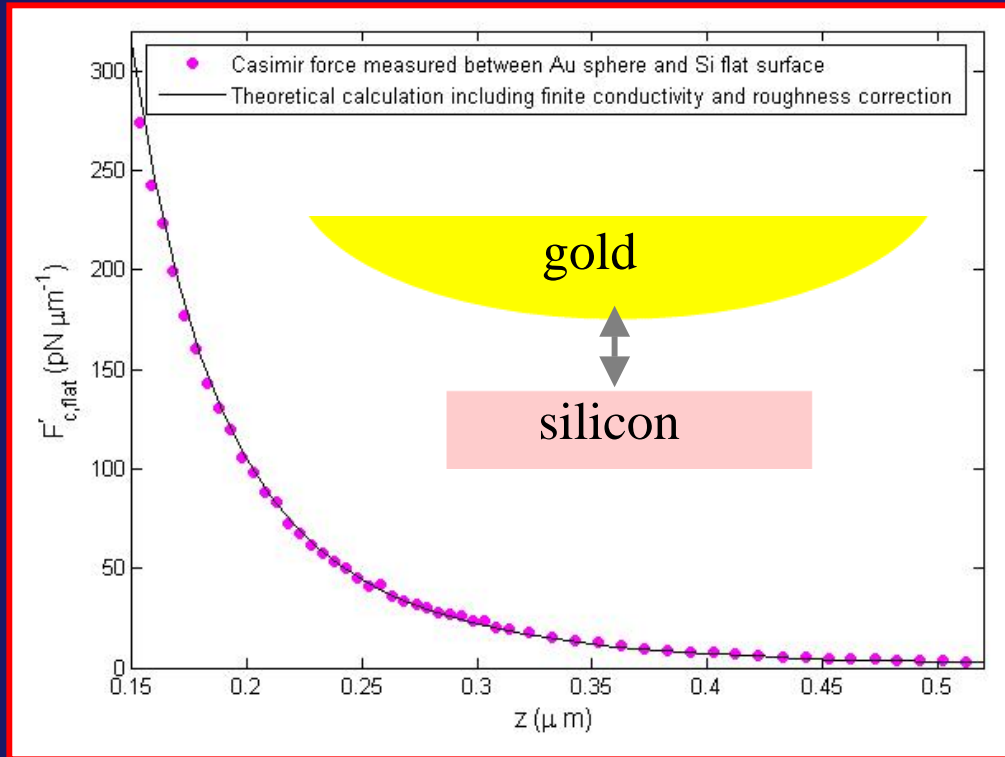
Corrugated surface



- Finite element analysis to solve 2D Poisson equation: $N > 10\ 000$ triangles
- Check convergence: double N changes force by 0.1%
- Proximity force approximation: $F_{\text{sphere-corrugate}} = 2 \pi R E_{\text{flat-corrugate}}$

Casimir force measurements

3 samples made from the same silicon wafer



Pairwise additivity:

$$F_{c,trench} = \frac{1}{2} F_{c,flat}$$

For all λ

For solid fraction p:

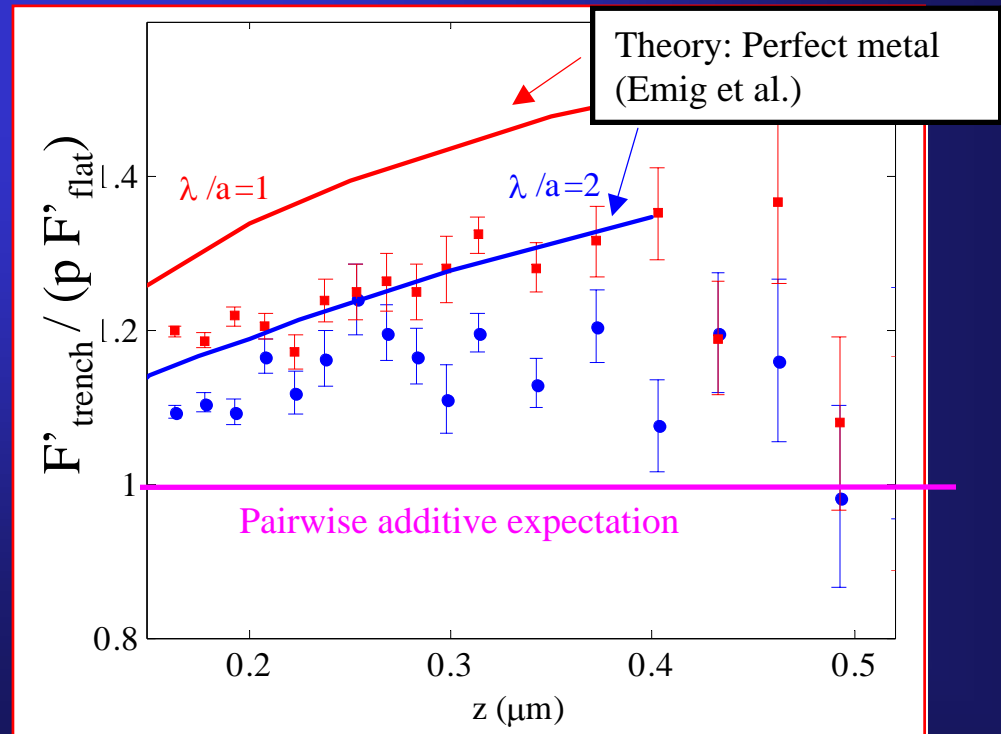
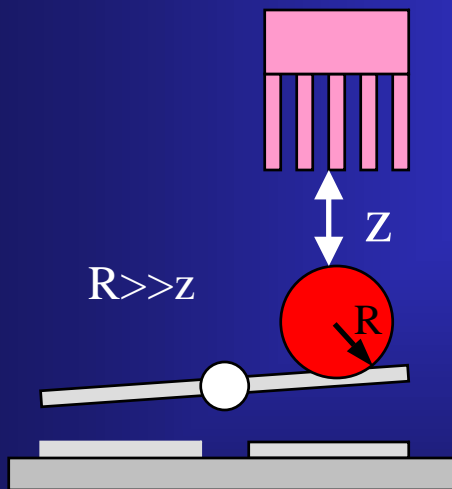
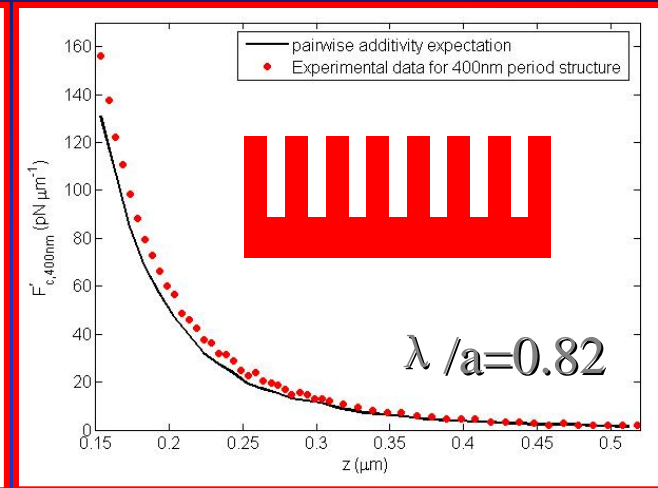
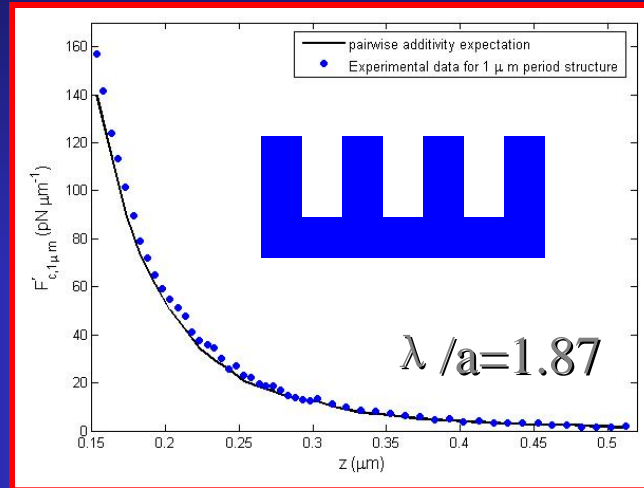
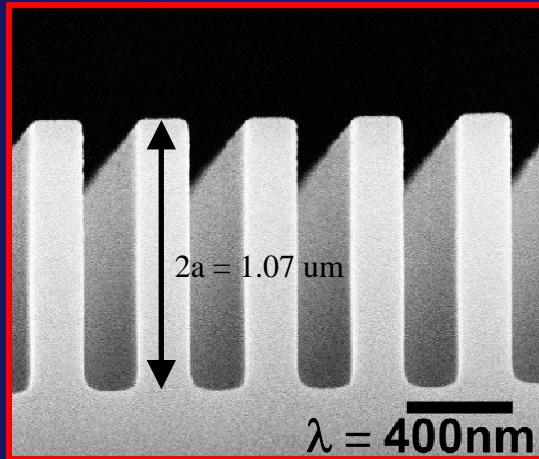
$$F_{c,trench} = p F_{c,flat}$$

For all material

Any deviation of measured force on corrugation from $pF_{c,flat}$

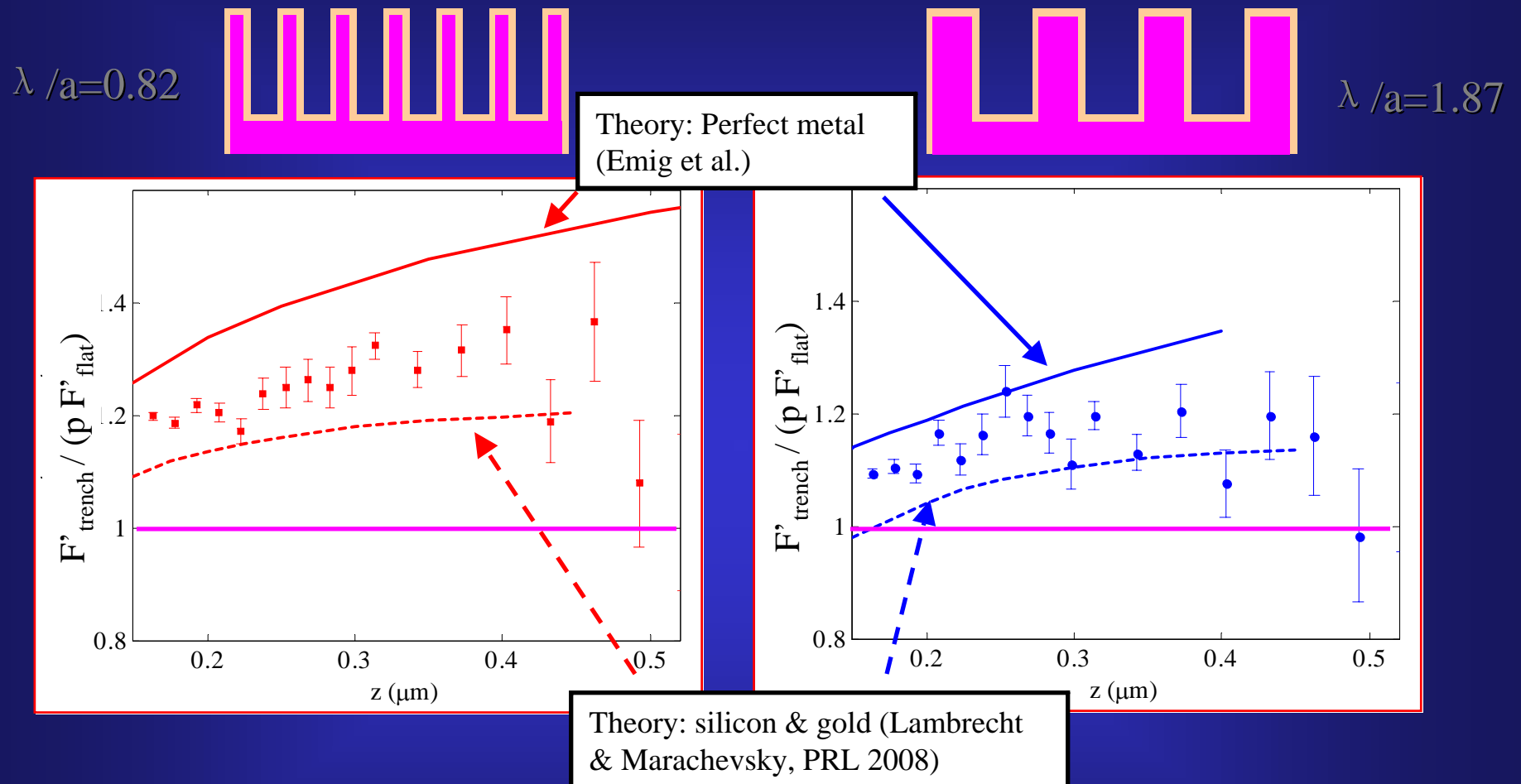
→ deviation from pairwise additivity (dependence of Casimir force on geometry)

Non-trivial boundary dependence of the Casimir force



Chan *et al.*, PRL 101, 030401 (2008).

Interplay of finite conductivity and geometry effects



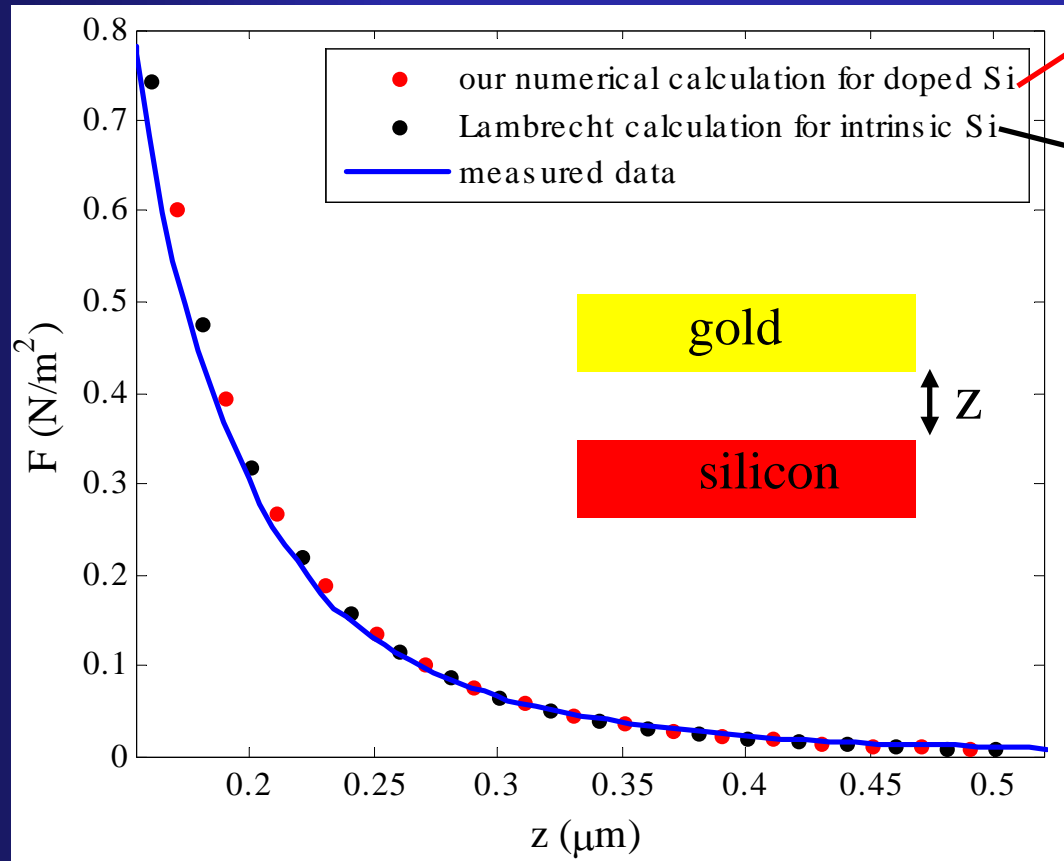
Lambrecht & Marachevsky 2008: includes both finite conductivity and geometry effects.

Using scattering theory.

Possible reason for discrepancy:

uncertainties in the optical properties of gold and silicon

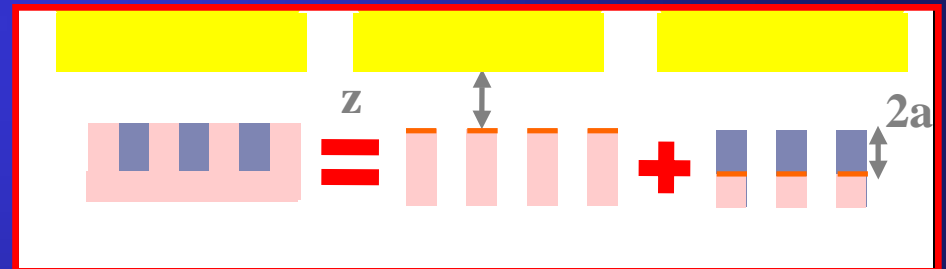
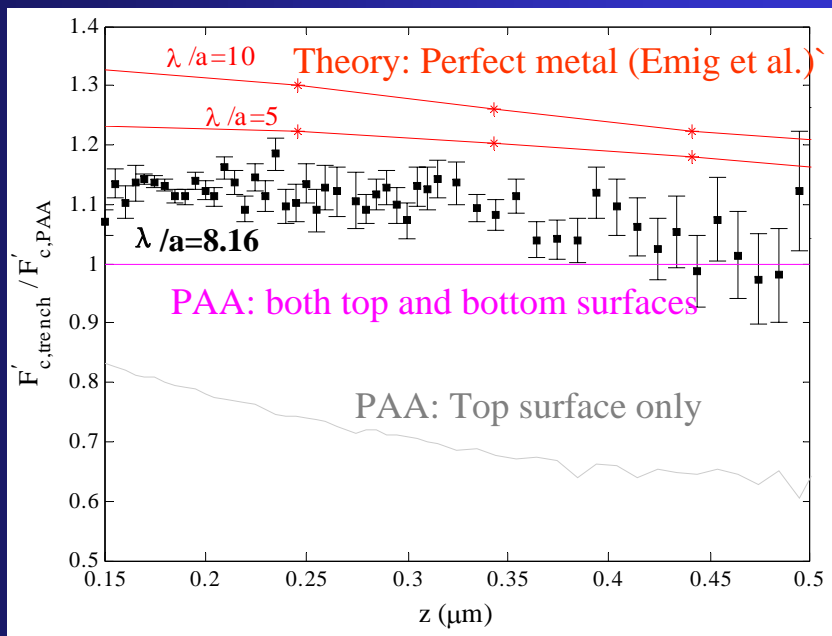
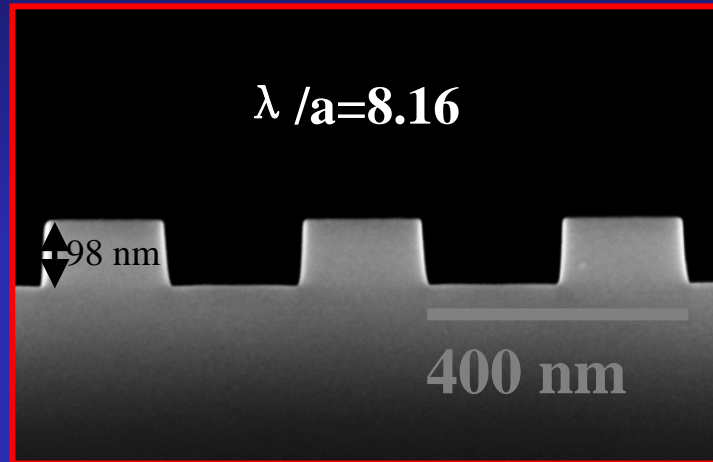
Consistency of measured force on flat plate with optical properties



Tabulated ϵ from Palik, modified by doping in silicon:
$$\epsilon_{silicon}(i\xi) = \epsilon_{undoped}(i\xi) + \frac{\omega_p}{\xi(\xi + \gamma)}$$

Plasma model for gold, Drude-Lorentz model for intrinsic silicon

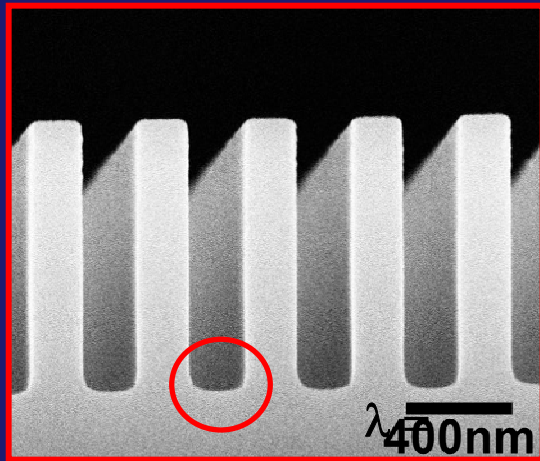
New experimental results: shallow trench arrays



For both PAA and PFA:

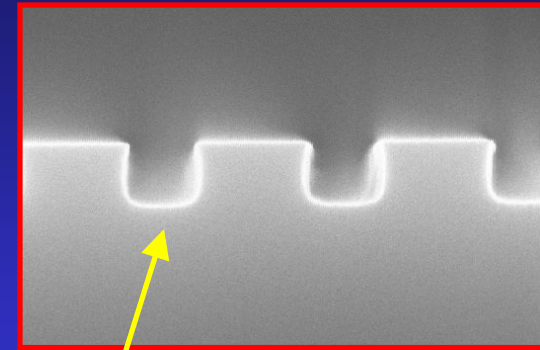
$$F_{c,trench}(z) = pF_{c,flat}(z) + (1-p)F_{c,flat}(z+2a)$$

Fabrication of shallow trench arrays

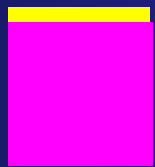


DRIE $\text{C}_4\text{F}_8 + \text{SF}_6$

Reduce etching time



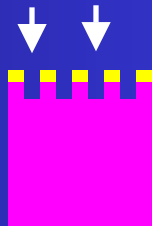
Rounded bottom



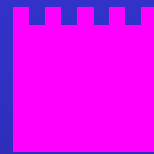
Oxide etch
mask



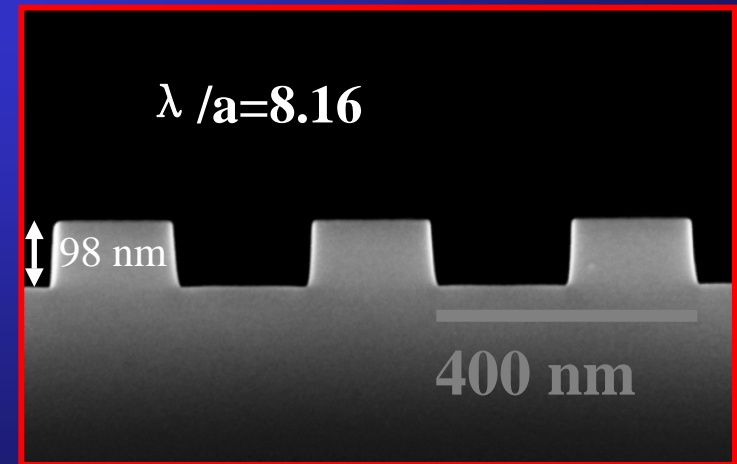
Deep UV litho



RIE



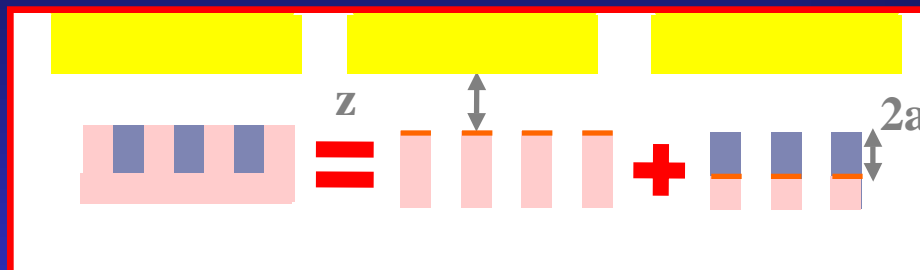
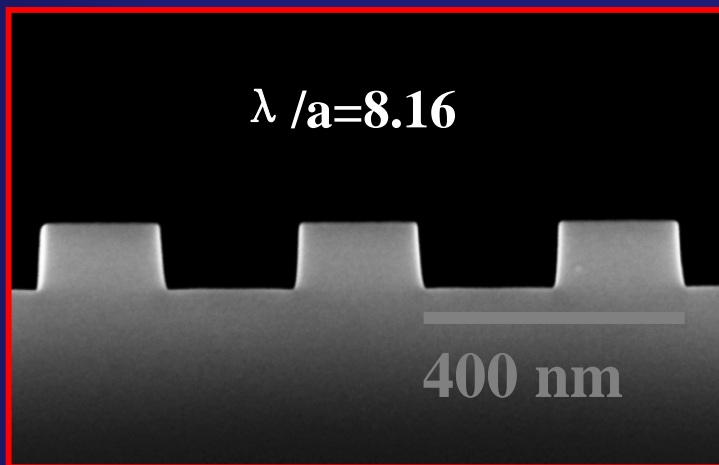
Etch
mask
removal



Modified etching recipe

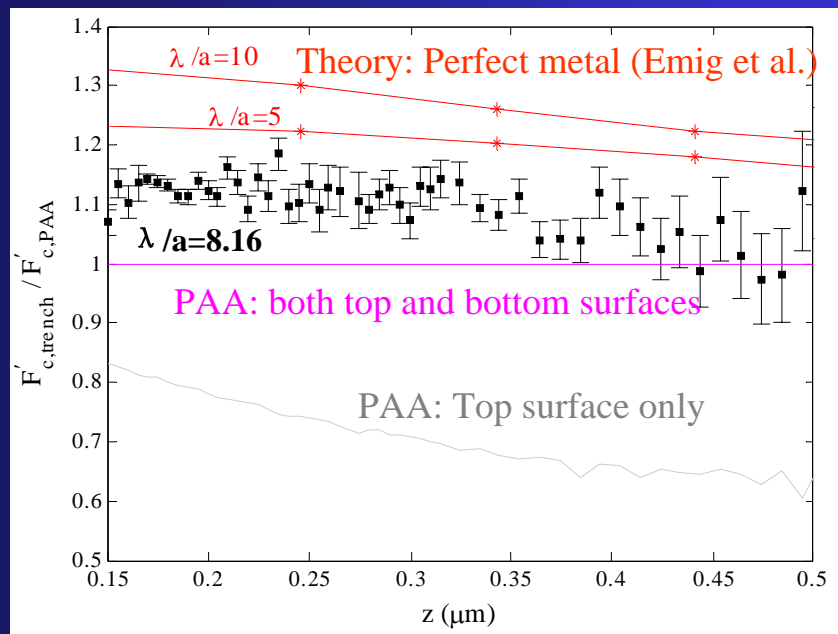
(ICP Ar + SF_6) to attain flat lower surface

PAA and PFA in shallow trench arrays



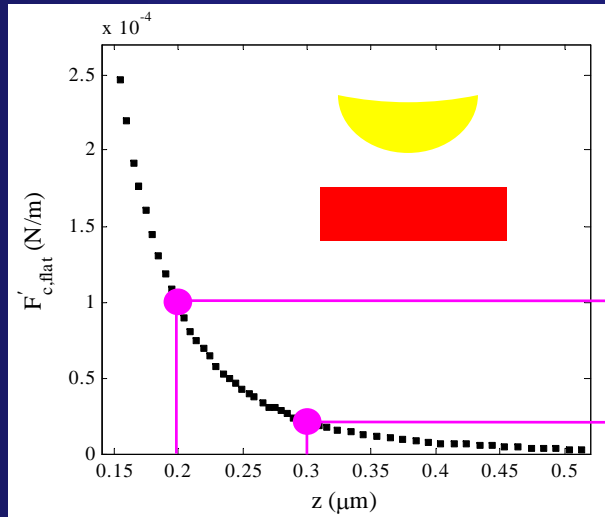
Pairwise additive approx (PAA)/proximity force approx (PFA):

$$F_{c,trench}(z) = pF_{c,flat}(z) + (1-p)F_{c,flat}(z + 2a)$$



Contribution of bottom surface not negligible
Easier for comparison to theory (perturbative approaches)

New experimental results: shallow trench arrays



PAA/PFA

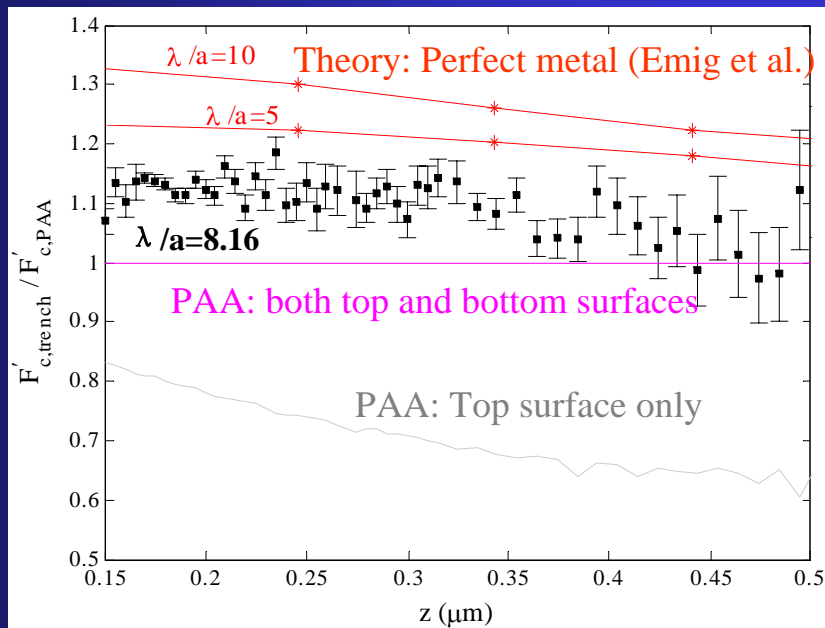
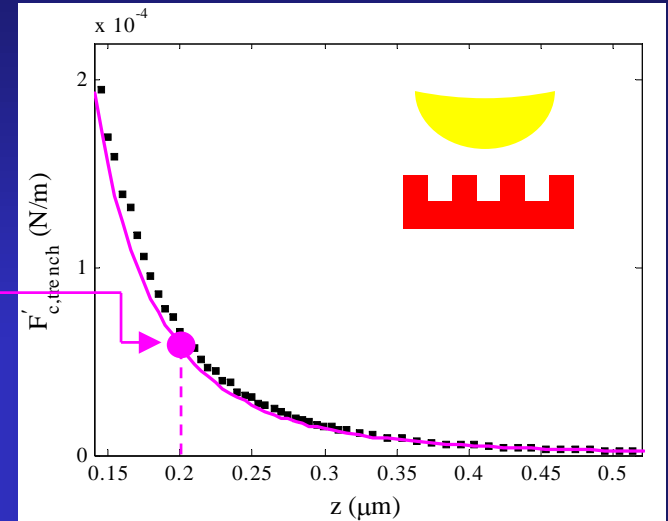
$$F_{c,flat}(z)$$

$$\times p$$

$$F_{c,flat}(z + 2a)$$

$$\times (1 - p)$$

$$+$$



Ongoing collaboration with Emig, Hanke and Johnson in calculating the Casimir force including finite conductivity.

Summary

- Experiment on strongly deformed surface:

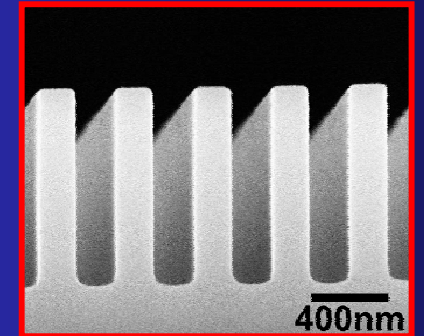
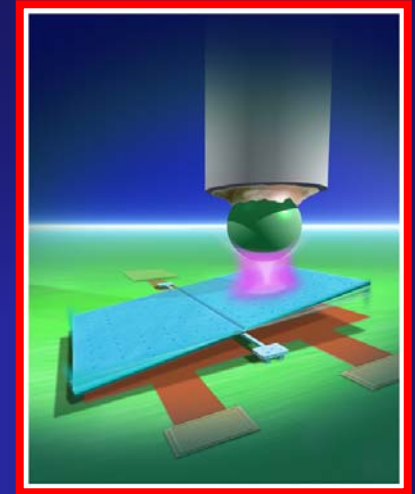
Measure Casimir force on an array of nanoscale trenches with a micromechanical torsional oscillator

Up to 30% deviation from PFA and PAA

Evidence of non-trivial boundary dependence of the Casimir force

~ 30% smaller than theory on perfect metals

~ 30% higher than theory on gold/silicon



Collaborators

University of Florida



Yiliang Bao



Jie Zou

University Paris-Sud
Thorsten Emig

UT Brownsville

Andreas Hanke

MIT

Steven Johnson

Bell Labs

Ray Cirelli

Fred Klemens

Bill Mansfield

C.S. Pai



DE-FG02-05ER46



DMR-0645448